

**ELECTRICAL PROPERTIES OF NIOBIUM DOPED TITANIUM
DIOXIDE THIN FILMS BY SPIN COATING TECHNIQUE**

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ABSTRACT

In this research, undoped TiO₂ and Niobium (Nb)-doped TiO₂ thin films have been successfully prepared and deposited on glass substrate by spin coating technique. The effect of annealing temperature on electrical properties using I-V measurement of Titanium Dioxide thin films was studied. TiO₂ thin films were annealed at 300°C to 550°C. The results indicated that the conductivity increased with the increasing of annealing temperatures. Using 450°C as an optimum annealing temperature, the effect of Nb doping concentrations on electrical properties was investigated. As the doping concentration of Nb was increased, conductivity was increased. Optical properties of TiO₂ thin films were investigated using UV-vis-NIR spectrophotometer and indicated that the optical band gap increased with increasing Nb doping concentration. The FESEM investigation showed that the thin films consist of nanometer-sized grain particles.

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CHAPTER 1

INTRODUCTION

1.1 PROJECT BACKGROUND

TiO₂ is well known as a metal oxide semiconductor, has been extensively studied in many applications and for example, it is used for dye-sensitized solar cells (DSSC), photo-electrodes and photocatalysts, and applications with high performance due to its fine physical, chemical and optical properties [1]. TiO₂ presents three crystalline structures: brookite, anatase, and rutile [2]. Titanium dioxide (rutile) has an extensive range of applications due to its interesting electrical and photo-electrical properties determined by nonstoichiometry and related point defect structure. Metal ion doping (by both acceptor- or donor-type elements) can significantly modify these properties. High-temperature semiconducting properties of undoped, acceptor- or donor- doped TiO₂ have been the subject of numerous reports [3].

TiO₂ is used widely as a gas sensing material due to its change in electrical conductivity under analyte gas exposure. Sensing capability has been improved with the addition of foreign atoms such as W, Pt and Cr, Mo and Nb, Fe, and Cu and La [4]. Many researchers have studied, and found that the properties of transition metal oxides can be enhanced by doping, which widens their potential applications. Nb doping modifies the microstructure of TiO₂, introduces electronic defects at the surface or in the bulk of grains, so modifies TiO₂ conductivity and gas sensing [4].

There are several techniques that are used to deposit undoped Nanostructured Titanium Dioxide thin film (UN) and Niobium doped nanostructured (NbDN) TiO₂ thin film such as RF-magnetron sputtering, pulsed laser deposition (PLD), metal-organic chemical vapor deposition (MOCVD), sol-gel process and spin coating method.